复合磁极磁粒研磨平面机理及试验探究

朱子俊,韩冰,陈燕,李奎

(辽宁科技大学 辽宁省复杂工件表面特种加工重点实验室,辽宁 鞍山 114051)

摘 要:目的 探究磁粒研磨中复合磁极磁回路对工件表面质量及表面粗糙度值的影响,解决传统平面磨粒 受磁力较小而远离加工区域,从而使表面质量较低的问题。方法 对提出的磁极复合磁路法进行研磨机理分 析,并通过磨粒在加工中的受力分析,进而分析影响因素。使用等效磁路法,对 3 种磁路所形成加工区域 的磁感应强度进行计算,进而采用 Ansoft Maxwell 软件对 3 种磁路的磁场梯度模拟仿真进行对比分析,综 合分析、评价影响因素的作用,为试验打下理论基础。最后使用表面粗糙度仪及超景深 3D 显微镜,对采用 不同磁回路研磨前后的工件表面粗糙度值及表面质量进行测量与记录。结果 复合磁极磁路中的磁感应强度 大于传统研磨加工,具有明显、对称的磁场梯度效果。与传统式研磨相对比,表面粗糙度值从 0.10 μm 降 至 0.06 μm,在表面粗糙度改善率上提升 40%,工件表面研磨质量较好。结论 复合磁极式磁粒研磨工艺对 工件表面的划痕、凹坑、斑点等达到了良好的去除效果,使工件表面平整并具有镜面效果,较传统研磨明 显具有质量好、效率高的优点。

关键词:复合磁极;磁粒研磨;等效磁回路;SUS304不锈钢;表面粗糙度值;表面微观形貌 中图分类号:TG356.28 文献标识码:A 文章编号:1001-3660(2021)09-0352-09 DOI: 10.16490/j.cnki.issn.1001-3660.2021.09.037

Mechanism Analysis and Experimental Study of Plane of Compound Magnetic Pole Magnetic Abrasive Lapping

ZHU Zi-jun, HAN Bing, CHEN Yan, LI Kui

(Liaoning Key Laboratory of Special Machining for Complex Workpiece Surface, University of Science and Technology Liaoning, Anshan 114051, China)

ABSTRACT: The work aims to explore the influence of compound magnetic pole magnetic circuit on the surface quality and surface roughness value of the workpiece in magnetic abrasive lapping and solve the problem that the traditional magnetic abrasive lapping in abrasive particles far away from the processing area due to the smaller magnetic force, which makes the workpiece surface quality is low. Firstly, the lapping mechanism of the composite magnetic pole magnetic circuit method is analyzed, and the influence factors are analyzed through the force analysis of the abrasive particles in the processing. The equivalent magnetic circuit method is used to calculate the magnetic induction intensity of the processing area formed by the

收稿日期: 2020-09-14; 修订日期: 2020-11-18

Received: 2020-09-14; Revised: 2020-11-18

基金项目: 国家自然科学基金 (51775258)

Fund: Supported by the National Natural Science Foundation of China (51775258)

作者简介:朱子俊(1995—),女,硕士研究生,主要研究方向为精密加工。

Biography: ZHU Zi-jun (1995—), Female, Master, Research focus: precision machining.

通讯作者:韩冰(1975—),男,博士,教授,主要研究方向为精密加工。

Corresponding author: HAN Bing (1975—), Male, Doctor, Professor, Research focus: precision machining.

引文格式:朱子俊,韩冰,陈燕,等.复合磁极磁粒研磨平面机理及试验探究[J]. 表面技术,2021,50(9):352-360.

ZHU Zi-jun, HAN Bing, CHEN Yan, et al. Mechanism analysis and experimental study of plane of compound magnetic pole magnetic abrasive lapping 4-2/21 Children Academic Journal Electronic Publishing House. All rights reserved. http://www.cnki.net